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PATENT
Attorney Docket No.: SSI-02001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Biberger et al.

Patent No. 6,890,853 B2
Serial No. 09/841,800

Issue Date: May 10, 2005
Filed: April 24, 2001

For: **METHOD OF DEPOSITING
FILM AND METAL
DEPOSITION CLUSTER TOOL
INCLUDING SUPERCRITICAL
DRYING/CLEANING MODULE**

) Group Art Unit: 2825

) Examiner: Caridad Everhart

) **TRANSMITTAL LETTER**

) 162 North Wolfe Road
) Sunnyvale, CA 94086
) (408) 530-9700) 833-0160

) Customer No.: 28960

**Attn: Decision and Certificate of Correction
Branch of the Patent Issue Division**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Certificate
JUN 14 2005
of Correction

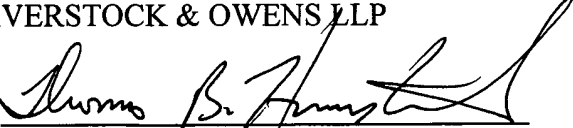
Sir:

Enclosed please find a Request for Certificate of Correction of the Patent, including form PTO-1050 in duplicate for filing with the U.S. Patent and Trademark Office. Also enclosed is a copy of the Information Disclosure Statement filed August 22, 2001 for reference purpose only.

The Commissioner is authorized to charge any additional fee or credit any overpayment to our Deposit Account No. 08-1275. **An originally executed duplicate of this transmittal is enclosed for this purpose.**

Respectfully submitted,

HAVERSTOCK & OWENS LLP

By: 
Thomas B. Haverstock
Reg. No. 32,571

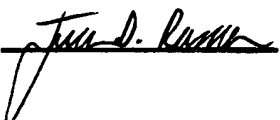
Dated: May 31, 2005

Attorneys for Applicant

CERTIFICATE OF MAILING (37 CFR § 1.8(a))

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450

HAVERSTOCK & OWENS LLP.

Date: 5-31-05 By: 

JUN 15 2005



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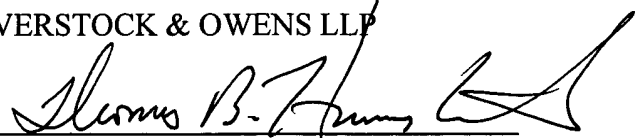
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HAVERSTOCK & OWENS LLP.

Date: 5-31-05 By: 

Attorneys for Applicant



PATENT
Attorney Docket No.: SSI-02001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
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Patent No. 6,890,853 B2
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DRYING/CLEANING MODULE**

) Group Art Unit: 2825

) Examiner: Caridad Everhart

) **REQUEST FOR CERTIFICATE OF
CORRECTION OF PATENT FOR PTO
MISTAKE UNDER 37 CFR 1.322(a)**

) 162 North Wolfe Road
Sunnyvale, CA 94086
(408) 530-9700) 833-0160

) Customer No.: 28960

**Attn: Decision and Certificate of Correction
Branch of the Patent Issue Division**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached in duplicate is Form PTO-1050 with at least one copy being suitable for printing. Further, a copy of the Information Disclosure Statement originally submitted August 22, 2001 is included for verification that the IDS was timely filed. It is our understanding, following a phone conversation on May 26, 2005 with Mr. Lamont Newsom, that this document will suffice to verify timely filing and allow consideration following release of the file to the Examiner. Please contact us as soon as possible if there is any issued or concerns regarding this understanding.

The exact page and line number where the errors are shown correctly in the application file are:

CERTIFICATE OF MAILING (37 CFR§ 1.8(a))

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450

HAVERSTOCK & OWENS LLP.

Date: 5-31-05 By: [Signature]

JUN 15 2005

In the References Cited

References from the Information Disclosure Statement mailed by the Applicants on August 22, 2001, which has not yet been properly considered by the Examiner, are to be added to the references cited.

In addition, a single reference from the Information Disclosure Statement electronically submitted by the Applicants on November 14, 2003 with EFS ID 50639, and considered by the Examiner on February 24, 2004, is to be added to the references cited.

Nineteen references from the Information Disclosure Statement mailed by the applicants on August 22, 2001 are to be added to the references cited:

--4,592,306	06/03/86	Gallego	118	719
4,670,126	06/02/87	Messer et al.	204	298
4,825,808	05/02/89	Takahashi et al.	118	719
4,951,601	08/28/90	Maydan et al.	118	719
5,934,856	08/10/99	Asakawa et al.	414	217
6,077,321	06/30/00	Adachi et al.	29	25.01
EP 0 244 951 A2	11/11/87	EP H 01 L	21/00	
EP 0 272 141 A2	06/22/88	EP H 01 L	21/00	
GB 2 193 482 A	02/10/88	GB B 25 J	18/02	
JP 10-144757	05/29/98	JP H 01 L	21/68	
JP 56-142629	11/07/81	JP H 01 L	21/205	
JP 60-238479	11/27/85	JP C 23 C	14/56	
JP 60-246635	12/06/85	JP H 01 L	21/302	
JP 61-231166	10/15/86	JP C 23 C	14/24	
JP 63-303059	12/09/88	JP C 23 C	14/22	
WO 87/07309	12/03/87	WO C 23 C	16/00	
WO 91/12629	08/22/91	WO H 01 L	21/00	
WO 99/186603	04/15/99	WO H 01 L	21/00	

Hideaki Itakura et al., "Multi-Chamber Dry Etching System", Solid State Technology, April 1982, pp. 209-214--.

One reference (No. 9) from the Information Disclosure Statement electronically submitted by the Applicants on November 14, 2003 with EFS ID 50639, and considered by the Examiner on February 24, 2004, is missing and is to be added to the references cited:

--6,001,133 12/14/1999 DeYoung et al. --.

In the Specification

In the Original Application, filed April 21, 2001:

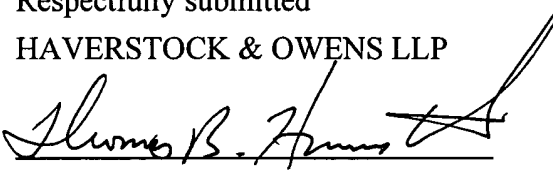
On page 1, line 7, replace "deposition of film" with --deposition of films--.

In the Claims

In the "Response to the Office Action dated August 21, 2003" which was mailed by the Applicants on November 21, 2003:

In Claim 13, replace "2,6-dimethylheptane-3,5-dione" with --2,6-dimethylheptane-3,5-dione--.

Dated: 5-31-05

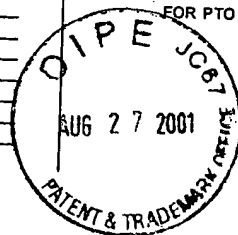
Respectfully submitted
HAVERSTOCK & OWENS LLP
By: 
Thomas B. Haverstock
Registration No.: 32,571
Attorneys for Applicant

COPY

Serial No.: 09/841,800 H&O File No.: SS1-02001 By: TBH/JR
in the Matter of This Application of Maximilian A. Biberger et al.
Date Mailed: August 22, 2001 Due Date:

The following has been received in the U.S. Patent and Trademark Office on the date stamped hereon:

- | | | | |
|--|---|--|---|
| <input type="checkbox"/> Design Patent Application _____ Pages | <input type="checkbox"/> Form PTO-1533 (Not. of Missing Parts) | <input checked="" type="checkbox"/> Transmittal Letter | <input checked="" type="checkbox"/> Duplicate |
| <input type="checkbox"/> Utility patent Application _____ Pages | <input type="checkbox"/> Form PTOL-85B (Issue Fee Trans) & dup. | <input checked="" type="checkbox"/> Certificate of Mailing | |
| <input type="checkbox"/> Prov. Patent Application _____ Pages | <input type="checkbox"/> Form PTO-1050 (Cert. of Correction) | <input type="checkbox"/> Certificate of Express Mailing | |
| <input type="checkbox"/> Declaration/Oath | <input type="checkbox"/> Maintenance Fee Transmittal Form | Label No.: _____ | |
| <input type="checkbox"/> Power of Attorney _____ | <input type="checkbox"/> Reexamination Request | <input type="checkbox"/> Check(s): \$ _____ | |
| <input type="checkbox"/> Assignment | <input type="checkbox"/> Notice of Appeal | <input checked="" type="checkbox"/> Deposit Account Authorization Form | |
| <input type="checkbox"/> Form PTO-1594/1595 | <input type="checkbox"/> Affidavit/Declaration | | |
| <input type="checkbox"/> Small Entity Declaration | <input type="checkbox"/> Copy of Filing Receipt | | |
| <input type="checkbox"/> Drawings: _____ Sheet(s) | <input type="checkbox"/> Req. for Corr. of: _____ | | |
| <input type="checkbox"/> <input type="checkbox"/> Formal <input type="checkbox"/> Informal | | | |
| <input checked="" type="checkbox"/> Information Disclosure Statement | | | |
| <input checked="" type="checkbox"/> Form PTO-1449 and Copies of | | | |
| References Contained Thereon | | | |
| <input type="checkbox"/> Information Disclosure Certification | | | |
| <input type="checkbox"/> Amendment/Response | | | |
| <input type="checkbox"/> Extension of Time Request: _____ Month(s) | | | |
| <input type="checkbox"/> Petition | | | |





COPY

Attorney Docket No.: PATENT
SSI-02001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Maximilian A. Biberger *et al.*

Serial No.: 09/841,800

Filed: April 24, 2001

For: **METHOD OF DEPOSITING
METAL FILM AND METAL
DEPOSITION CLUSTER TOOL
INCLUDING SUPERCRITICAL
DRYING/CLEANING MODULE**

) Group Art Unit: 2812

) Examiner:

) **TRANSMITTAL LETTER**

) 260 Sheridan Avenue, Suite 420
) Palo Alto, California 94306
) (650)833-0160

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Enclosed please find a Supplemental Information Disclosure Statement, and Form PTO-1449, including copies of the references contained thereon, for filing in the U.S. Patent and Trademark Office.

The Commissioner is hereby authorized to charge any additional fee or credit overpayment to our Deposit Account No. 08-1275. **An originally executed duplicate of this transmittal is enclosed for this purpose.**

Respectfully submitted,
HAVERSTOCK & OWENS LLP

Dated: 8-21-01

By: Thomas B. Haverstock
Thomas B. Haverstock
Reg. No.: 32,571

Attorneys for Applicants

CERTIFICATE OF MAILING (37 CFR § 1.8(a))

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the: Assistant Commissioner for Patents, Washington D.C. 20231

- 1 -

HAVERSTOCK & OWENS LLP

Date: 8/22/2001 By: Thomas D. Russeau



Attorney Docket No.: PATENT
SSI-02001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Maximilian A. Biberger *et al.*

Serial No.: 09/841,800

Filed: April 24, 2001

For: **METHOD OF DEPOSITING
METAL FILM AND METAL
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) **TRANSMITTAL LETTER**

) 260 Sheridan Avenue, Suite 420
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) (650)833-0160

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Enclosed please find a Supplemental Information Disclosure Statement, and Form PTO-1449, including copies of the references contained thereon, for filing in the U.S. Patent and Trademark Office.

The Commissioner is hereby authorized to charge any additional fee or credit overpayment to our Deposit Account No. 08-1275. **An originally executed duplicate of this transmittal is enclosed for this purpose.**

Respectfully submitted,
HAVERSTOCK & OWENS LLP

Dated: 8/21/01

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Reg. No.: 32,571

Attorneys for Applicants

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- 1 -

HAVERSTOCK & OWENS LLP

Date: 8/24/01 By: Thomas B. Haverstock



COPY

Attorney Docket No.: PATENT
SSI-02001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Maximilian A. Biberger *et al.*

Serial No.: 09/841,800

Filed: April 24, 2001

For: **METHOD OF DEPOSITING
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INCLUDING SUPERCRITICAL
DRYING/CLEANING MODULE**

) Group Art Unit: 2812

) Examiner:

) **SUPPLEMENTAL INFORMATION**
) **DISCLOSURE STATEMENT**

) 260 Sheridan Avenue, Suite 420
) Palo Alto, California 94306
) (650)833-0160

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

The citations listed below, copies attached, may be material to the examination of the above-identified application, and are therefore submitted in compliance with the duty of disclosure defined in 37 C.F.R. §§ 1.56 and 1.97. The Examiner is requested to make these citations of official record in this application.

Applicants have become aware of the following printed publications which may be material to the examination of this application:

- U.S. Patent No. 4,592,306;
- U.S. Patent No. 4,670,126;
- U.S. Patent No. 4,825,808;
- U.S. Patent No. 4,951,601;
- U.S. Patent No. 5,934,856;
- U.S. Patent No. 6,077,321;
- European Publication No. EP 0 244 951 A2;
- European Publication No. EP 0 272 141 A2;
- Great Britain Publication No. GB 2 193 482 A;



COPY

Attorney Docket No.: PATENT
SSI-02001

- Japanese Patent Abstract JP 10-144757;
- Japanese Patent Abstract JP 56-142629;
- Japanese Patent Abstract JP 60-238479;
- Japanese Patent Abstract JP 60-246635;
- Japanese Patent Abstract JP 61-231166;
- Japanese Patent Abstract JP 63-303059;
- PCT Publication No. WO 87/07309;
- PCT Publication No. WO 91/12629;
- PCT Publication No. WO 99/18603; and
- Hideaki Itakura et al., "Multi-Chamber Dry Etching System", Solid State Technology, April 1982, Page. 209-214.

This Supplemental Information Disclosure Statement under 37 C.F.R. §§ 1.56 and 1.97 is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that anyone or more of these citations constitutes prior art.

Respectfully submitted,
HAVERSTOCK & OWENS LLP

Dated: 8-21-01

By: Thomas B. Haverstock
Thomas B. Haverstock
Reg. No.: 32,571

Attorneys for Applicants

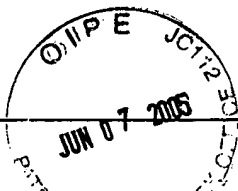
CERTIFICATE OF MAILING (37 CFR § 1.8(a)),

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- 2 -

HAVERSTOCK & OWENS LLP.

Date: 8/22/01 By: Thomas B. Haverstock



COPY

FORM PTO-1449 (Modified)		U.S. Department of Commerce Patent and Trademark Office		Attorney Docket No.: SSI-02001		Serial No.: 09/841,800		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary) (37 CFR § 1.98(b))				Applicant: Maximilian A. Biberger <i>et al.</i>				
				Filing Date: April 24, 2001		Group Art Unit: 2812		
U.S. PATENT DOCUMENTS								
Examiner Initials		Serial / Patent Number	Issue Date	Applicant / Patentee	Class	Subclass	Filing Date	
	AA	4,592,306	06/03/86	Gallego	118	719	11/30/84	
	AB	4,670,126	06/02/87	Messer <i>et al.</i>	204	298	04/28/86	
	AC	4,825,808	05/02/89	Takahashi <i>et al.</i>	118	719	07/08/87	
	AD	4,951,601	08/28/90	Maydan <i>et al.</i>	118	719	06/23/89	
	AE	5,934,856	08/10/99	Asakawa <i>et al.</i>	414	217	04/28/97	
	AF	6,077,321	06/30/00	Adachi <i>et al.</i>	29	25.01	11/07/97	
FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS								
		Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation	
							Yes	No
	AG	EP 0 244 951 A2	11/11/87	EP	H 01 L	21/00		x
	AH	EP 0 272 141 A2	06/22/88	EP	H 01 L	21/00		x
	AI	GB 2 193 482 A	02/10/88	GB	B 25 J	18/02		x
	AJ	JP 10-144757	05/29/98	JP	H 01 L	21/68		x
	AK	JP 56-142629	11/07/81	JP	H 01 L	21/205		x
	AL	JP 60-238479	11/27/85	JP	C 23 C	14/56	x	
	AM	JP 60-246635	12/06/85	JP	H 01 L	21/302		x
	AN	JP 61-231166	10/15/86	JP	C 23 C	14/24		x
	AO	JP 63-303059	12/09/88	JP	C 23 C	14/22		x
	AP	WO 87/07309	12/03/87	WO	C 23 C	16/00		x
	AQ	WO 91/12629	08/22/91	WO	H 01 L	21/00		x
	AR	WO 99/186603	04/15/99	WO	H 01 L	21/00		x
OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)								
	AS	Hideaki Itakura <i>et al.</i> , "Multi-Chamber Dry Etching System", Solid State Technology, April 1982, pp. 209-214.						
	AT							
	AU							
	AV							
	AW							
	AX							
	AY							
Examiner:				Date Considered:				
EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								